

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :
Makoto AKIZUKI et al. :
Serial No. [NEW] : **Attn: APPLICATION BRANCH**
Filed December 26, 2001 : Attorney Docket No. 2001-1897

METHOD FOR FORMING GAS CLUSTER
AND METHOD FOR FORMING THIN FILM

(Rule 1.53(b) Continuation of Serial
No. 09/799,681, Filed March 7, 2001)

CLAIM OF PRIORITY UNDER 35 USC 119

Assistant Commissioner for Patents,
Washington, DC 20231


Sir:

Applicants in the above-entitled application hereby claim the dates of priority under the International Convention of Japanese Patent Application No. 121983/1995, filed May 19, 1995, Japanese Patent Application No. 244957/1995, filed September 22, 1995, and Japanese Patent Application No. 064861/1996, filed March 21, 1996 as acknowledged in the Declaration of this application.

Certified copies of said Japanese Patent Applications are of record in the parent application, Serial No. 09/566,740, filed May 9, 2000.

Respectfully submitted,

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